## Solid State Sensor Poster Review





27 posters in 20 minutes → 44,44 secs / topic Be prepared ⓒ

## Overview



ATLAS	Alignment of the ATLAS Inner Detector Tracking System
	ATLAS Silicon Microstrip Tracker Commissioning and Silicon Sensor Performance
	Results from the Commissioning of the ATLAS Pixel Detector with Cosmics Data
CMS	Data Quality Monitoring of the CMS Silicon Strip Tracker Detector
	CMS Silicon Strip Tracker Operation in Cosmic Run at Four Tesla
ALICE	The Silicon Drift Detector of the ALICE Experiment
	The ALICE Silicon Pixel Detector Read-Out Electronics
LHCB	First Experience and Results with the LHCb Silicon Tracker
CDF	Longevity Studies in the CDF Silicon Detectors
	Operational Experience with the CDF Run II Silicon Detector
Future detectors (e.g. B-	Go and fetch in 8 inc
factories)	Silicon vertex detector upgrade for SuperKEKB factory
	The SuperB Silicon Vertex Tracker
	Production and Performance of the Silicon Sensor and Custom Readout Electronics for the PHENIX FVTX Tracker
	The NA62 Gigatracker Pixel Detector System
3D & RD	3D Silicon Detectors for LHC Upgrades
	Characterization and Modelling of Signal Dynamics in 3D-DDTC Detectors
	Recent Advances in the Development of Semiconductor Detectors for Very High Luminosity Colliders
	Characterization of Irradiated P-Type Silicon Detectors by the ALIBAVA System
	Simulation of Electrical Parameters of New Design of SLHC Silicon Sensors for Large Radii
SLIM	SLIM5 Beam Test Results for Thin Striplet Detector and Fast Readout Beam Telescope
	Investigation of an abnormal pattern of the strip leakage currents in microstrip detectors
"other devices"	Laser and Alpha Particle Characterization of a Floating-Base BJT Detector
	Study of Geiger Avalanche Photo Diodes (GAPD) Applications to Pixel Tracking Detectors
	Characterization of CMOS Active Pixel Sensors for Particle Detection: Beam Test of the Four Sensors RAPS03 Stacked System
	Development and Experimental Characterization of Prototypes for Low Material Budget Support Structure and Cooling of Silicon
Generic supporting studies	Pixel Detectors, Based on Microchannel Technology
	Optimising the Strip Geometry for very Fine Pitch Silicon Strip Sensors
	Lithium Diffusion into Silicon-Germanium Single Crystal

Unfortunately not all slides nor posters are in Indico, Fortunately I have a digital camera. I tried my best.

## LHC DETECTORS



Regina Moles (IFIC – Valencia)

### ALIGNMENT OF THE ATLAS INNER DETECTOR TRACKING

Heinz Pernegger (CERN Physics Department)

### ATLAS SILICON MICROSTRIP TRACKER COMMISSIONING AND SILICON SENSOR PERFORMANCE

Jens Weingarten (*Dortmund University*)

## RESULTS FROM THE COMMISSIONING OF THE ATLAS PIXEL DETECTOR WITH COSMICS DATA

A summary was already given on Monday, more details on the posters They are really worth three looks (each)!



#### ALIGNMENT



 Assembly and survey measurements: External measurements of the as-built detecto
 Frequency Scanning Interferometry: SCT is equipped with a laser alignment monitoring system
 Track based alignment algorithms:

To achieve the ul>mate precision (μm)

The use of real cosmic ray data has allowed us to obtain a first set of alignment constants for the real detector.

The ATLAS ID is ready to reconstruct the first LHC collision tracks.





Bundesministerium für Bildung und Forschung

d Forschung

# Heinz Pernegger (CERN Physics Department) ATLAS Silicon Microstrip Tracker Commissioning and Silicon Sensor Performance

- Commissioned ATLAS Silicon Strip SCT during 2008
  - Stable readout in ATLAS with low noise
  - Test SCT tracking performance with Cosmics
- Readout in 2008 99% of Barrel and 97% of Endcap modules
- Efficiency >99%
- Noise Occupancy ~2-5 x10<sup>-5</sup> (specs 5x 10<sup>-4</sup>)
- First round of alignment with cosmics tracks (2M tracks in SCT) very sucessful





2 CMS poster, both very detailed

Leonardo Benucci (University of Antwerp)

## DATA QUALITY MONITORING OF THE CMS SILICON STRIP TRACKER DETECTOR

Vitaliano Ciulli ((Univ. di Firenze e Sez. dell' INFN,)

## CMS SILICON STRIP TRACKER OPERATION IN COSMIC RUN AT FOUR TESLA

### Data Quality Monitoring of the CMS Silicon Strip Tracker Detector

Leonardo Benucci - University of Antwerp, Belgium

Data Quality Monitoring (**DQM**) is being built to provide complete and coherent monitoring data (online and offline) at low latency, to ensure the optimal working of the hardware and software and to certify the quality of the data for analysis in an efficient way





#### Summaries of both topics have been presented in the general session on Monday, details on the poster





Mario Sitta (INFN - Torino)

# The Silicon Drift Detector of the ALICE Experiment

Marian Krivda (*IEP - Košice*)

## THE ALICE SILICON PIXEL DETECTOR READ-OUT ELECTRONICS





1 LHCB Poster

Vincent Fave (EPFL)

## FIRST EXPERIENCE AND RESULTS WITH THE LHCB SILICON TRACKER



#### TED Data

- This is the main data-set so far. The particles are produced by dumping injection test bunched in a tungsten absorber 300m 'behind' LHCb.
- TED events are high multiplicity events, with an occupancy 20 times greater than in normal physics.
- It has been used for the spatial alignment of IT and TT, beyond the survey results that is 500µm accurate for boxes and 100µm for Layers and Ladders.



## THESE LHC DETECTORS ARE PROBABLY OVERCOMMISSIONED ③



Miguel Mondragon (Fermilab)

## OPERATIONAL EXPERIENCE WITH THE CDF RUN II SILICON DETECTOR

Roberto Martinez-Ballarin (*CIEMAT-Madrid*)

## LONGEVITY STUDIES IN THE CDF SILICON DETECTORS

\* Where LHC detectors can learn from



### **Operational Experience with the CDF Run II Silicon Detector**



### THE LEARNING OF EIGHT YEARS OF OPERATIONS





### Longevity Studies in the CDF Silicon Detectors



A real life study about radiation damage in silicon

The inner layers already passed the point of space charge inversion

→ depletion voltage increases but will still stay for a while below the applicable bias voltages

B-factories In alphabetical order

Samo Stanic (University of Nova Gorica)

## SILICON VERTEX DETECTOR UPGRADE FOR SUPERKEKB FACTORY

Not yet waiting for beam

Giuliana Rizzo (Università di Pisa/INFN)

## THE SUPERB SILICON VERTEX TRACKER

Design progresses Both will use additionally pixel sensor Several technology choices under evaluation Hybrid pixels, DEPFET, CMOS, SOI (SOIPix; CAP) Somehow also a test bench for ILC detectors

#### Silicon Vertex Detector Upgrade for the **Belle II Experiment**

S. Stanič for the Belle SVD Group

#### Physics at extreme luminosity SuperKEKB collider:

 $(8.10^{35}/\text{cm}^2/\text{s} \text{ after upgrade}, \sim 2.10^{34}/\text{cm}^2/\text{s} \text{ presently achieved by}$  $KEKB \Rightarrow Realistic!)$ 

Precision measurements of CPV in B decays •Study of time dependence of B<sup>0</sup> - anti-B<sup>0</sup> decays •Study of rare decay modes of beauty and charm hadrons and  $\tau$ 

#### **Design requirements for the Silicon Tracker:**

Good resolution in the beam direction

•Small amount of material inside the acceptance region •Operation at high radiation background rates and high

track density (40 x present)

11/27



•SVD - Strip Detector (4 outer layers) - larger acceptance

Year



#### SVD Layout:

•System size 3-4x of the present Belle SVD2 (4 layers) •Use of DSSD sensors from 6" wafer, well established technology

•Additional use of alternative "chip-on-sensor" sensor types (Lower number of readout chips, less material and power dissipation in acceptance region)

•Readout with APV25 (~ 50ns shaping time, sensitive window ~160ns)+ FADC+COPPER (Full DAO chain already successfully tested in a beam test at KEK)

**Conceptually proven**, after finalizing the geometry ready for production.

#### Belle II PXD Layout (based on DEPFET):

- •Small radius, as close as possible to the beampipe
- •High granularity sensors, pixel size about  $50 x 75 \mu m^2$
- •Small detector 20-24 single sensor modules in two layers
- •Total of ~6Mpixel, frame readout rate <10 $\mu$ s
- •Possibility of variable pixel in z pitch to optimize charge sharing at large z and improve resolution in the central part



#### Done:

- -Successful beam tests
- -Rad. hardness tests (80kGy): low noise
- -GEANT4 simulation started

#### To do:

-Solve radiation related issues (threshold voltage shift is large)

-Consider mechanics/cooling design

-Consider DAQ interface (PXD may deliver up to 70Gbit/s)



#### PXD Sensor R&D Status - 3 variants pursued:

## •CAP, KEK SOIPIX (promising concepts, at basic R&D) •DEPFET (Most promising candidate -

Evolving from basic R&D to production for Belle II) -Pixel is a p-channel FET on a completely depleted bulk, deep n-implant creates a potential minimum for electrons under the gate -50 x (75-115) μm<sup>2</sup> pixels

-Frame readout time  ${<}10\mu s,$  sequential readout of pixels or rows -Low power, ASICs at the periphery







jon kapustinsky (Los Alamos National Lab)

## PRODUCTION AND PERFORMANCE OF THE SILICON SENSOR AND CUSTOM READOUT ELECTRONICS FOR THE PHENIX FVTX TRACKER



A custom front-end chip, the FPHX, has been designed for the FVTX by the ASIC Design Group at Fermilab. The chip combines fast trigger capability with data push architecture in a low power design. The chip was fabricated in the TSMC 0.25 micron CMOS process



Notto Scale

Giovanni Mazza (INFN - Torino)

## THE NA62 GIGATRACKER PIXEL DETECTOR SYSTEM



Giovanni Mazza (INFN - Torino)

## THE NA62 GIGATRACKER PIXEL DETECTOR SYSTEM





GigaTracker : 3 silicon pixel sensor stations for precise measurement of particle direction and timing.

Pixel size :  $300 \ \mu m \times 300 \ \mu m$ Sensitive area :  $27 \ mm \times 60 \ mm$ Time resolution :  $150 \ ps \ rms$  (total)  $200 \ ps \ rms$  (per station) Data rate :  $0.8 \div 1 \ \text{GHz}$  (total)  $1.5 \ \text{MHz/mm}^2$  (max) Operational environment : vacuum

Detector to be operated below 5 °C to keep the leakage current under control

Design challenge : obtain a 200 ps resolution with silicon pixel detectors at very high particle rate.

11th Pisa Meeting on Advanced Detectors - 24-30 May 2009



## **ASIC prototypes**



### Two readout options are under investigation :

Pixel matrix :  $40 \times 45$  cells.

Time walk compensation : Constant Fraction Discriminator (CFD).

Time measurement : on pixel TAC based TDC. Reference clock : 160 MHz.

Four event buffers for data derandomization (on pixel).

SEU protected control logic.

- + each pixel operate independently.
- + only one long distance time critical signal (clock).
- complex pixel circuitry.
- more control logic on the beam trajectory.

Pixel matrix : 40 × 45 cells.
Time walk compensation : Time over Threshold (ToT) correction.
Time measurement : DLL based TDC at the end of the pixel column.
Reference clock : 320 MHz.
Pre-emphasis for signal transmission.
+ simple and low power pixel circuitry.
+ only one DLL based TDC needed ( plus column registers ).
many time critical signals to be sent to the

EoC (one per pixel).

hit arbitration needed (possible event loss).

→ Prototypes of the analog part for the two options (preamp+CFD and ToT correction) have been designed in CMOS 0.13 µm and successfully tested.
 → Two test chip with the full pixel and column circuits are currently in production 11<sup>th</sup> Pisa Meeting on Advanced Detectors - 24-30 May 2009

various

3D & RD

3D gets more and more mature!

## **3D SILICON DETECTORS FOR LHC UPGRADES**

CINZIA DAVIA (THE UNIVERSITY OF MANCHESTER)



Measured to be ~4 microns

Cinzia Da Via/Manchester May 2009

### Highlights from test beams



Radiation hard due to high field and short inter-electrode spacing

test beam shows 99.0% efficiency at 15° from incoming beam -



Cinzia Da Via/Manchester May 2009

### Key processing steps (25-32)



WAFER BONDING (mechanical stability) Si-OH + HO-Si -> Si-O-Si + H<sub>2</sub>O

#### 1- etching the electrodes



Step 1-3 oxidize and fusion bond wafer



Step 4-6 pattern and etch p<sup>+</sup> window contacts



Step 7-8 etch p\* electrodes

#### 2-filling them with dopant<u>s</u>



Step 9-13 dope and fill p\* electrodes



Step 14-17 etch n\* window contacts and electrodes

Step 18-23 dope and fill n\* electrodes



Step 24-25 deposit and pattern Aluminum

Cinzia Da Via/Manchester May 2009

#### Aspect ratio; D;d = 11;1



LOW PRESSURE CHEMICAL VAPOR DEPOSITION (Electrodes filling with conformal doped polysilicon SiH4 at ~620C) 2P<sub>2</sub>O<sub>5</sub> +5 Si-> 4P + 5 SiO<sub>2</sub> 2B<sub>2</sub>O<sub>3</sub> +3Si -> 4 B +3 SiO<sub>2</sub>





METAL DEPOSITION Shorting electrodes of the same type with Al for strip electronics readout or deposit metal for bump-bonding





DEEP REACTIVE ION ETCHING (STS) (electrodes definition) Bosh process SiF<sub>4</sub> (gas) +C<sub>4</sub>F<sub>8</sub> (teflon)

Andrea Zoboli (*Università di Trento*)

## CHARACTERIZATION AND MODELLING OF SIGNAL DYNAMICS IN 3D-DDTC DETECTORS



### MIP penetrating from (30,30,0)



- MIP penetrating the device from (30,30,0)
- Evaluation of the current signal
- Two dimensional domain
- Full depletion not reached at the bottom
- Slow tail due to diffusion

Very interesting, have a look

Frank Hartmann (*IEKP Karlsruhe*)

### RECENT ADVANCES IN THE DEVELOPMENT OF SEMICONDUCTOR DETECTORS FOR VERY HIGH LUMINOSITY COLLIDERS



- For fluences above ~ 10<sup>15</sup> neq/cm<sup>2</sup> trapping becomes the dominant problem (depletion voltage remains important but less relevant)
- n-strip readout (n-in-n or n-in-p) looks very promising at least for outer layer, probably even for inner with higher voltage
- At high fluences p-material does not anneal with respect to CCE (maintenance periods easier to control?)
- It seems, that in MCz material charged particles introduces more donor and neutral more particle acceptor levels -> compensation
- 3D detectors are promising candidates for the very inner layers (enormous progress by several groups)
- Systematic studies of RD50 and WODEAN improves or understanding of microscopic defects to macroscopic device behaviour

Mercedes Miñano (Instituto de Física Corpuscular (IFIC))

**Barcelona** 

## CHARACTERIZATION OF IRRADIATED P-TYPE SILICON DETECTORS BY THE ALIBAVA SYSTEM

Liverpool

Valencia

#### Characterization of Irradiated P-type Silicon Detectors by the ALIBAVA System

Irradiated test sensors have been characterized in terms of their charge collection efficiency. A new acquisition system

• <u>The sensors</u>: High resistivity N-or Area 1 cm<sup>2</sup>

• <u>The ALIBAVA acquisition system:</u> a Beetle based system to read out t in strip silicon detectors by illumina radiation sources.







 $\rightarrow$  n-in-p is a viable option for SLHC



have been irradiated with on and proton irradiation expected doses of the ded Large Hadron Collider r-LHC) minosity peak: 10<sup>35</sup> cm<sup>-2</sup> s<sup>-1</sup>





Protons

Central European Consortium

- Aachen
- Desy
- Hamburg
- Karlsruhe
- Louvain La Neuve
- Santander
- Vienna
- Vilnius
- Warsaw

Otilia Militaru (Université Catholique de Louvain)

## SIMULATION OF ELECTRICAL PARAMETERS OF NEW DESIGN OF SLHC SILICON SENSORS FOR LARGE RADII



#### Simulation of electrical parameters of new design of SLHC silicon sensors for large radii



O. Militaru<sup>5)</sup>, T. Bergauer<sup>7)</sup>, M. Bergholz<sup>2)</sup>, P. Blüm<sup>4)</sup>, W. de Boer<sup>4)</sup>, K. Borras<sup>2)</sup>, E. Cortina Gil<sup>5)</sup>, A. Dierlamm<sup>5)</sup>, M. Dragicevic<sup>7)</sup>, D. Eckstein<sup>3)</sup>, J. Erfle<sup>4)</sup>, M. Fernandez<sup>6)</sup>, L. Feld<sup>1)</sup>, M. Frey<sup>4)</sup>, M. Friedl<sup>7)</sup>, E. Fretwurst<sup>3)</sup>, E.Gaubas<sup>8)</sup>, F. J. Gonzalez<sup>6)</sup>, P.Grabiec<sup>9)</sup>, M. Grodner<sup>9)</sup>, F. Hartmann<sup>4)</sup>, S. Hänsel<sup>7)</sup>, K-H Hoffmann<sup>4)</sup>, J. Hrubec<sup>7)</sup>, R.Jaramillo<sup>6)</sup>, W. Karpinski<sup>1)</sup>, V.Kazukauskas<sup>8)</sup>, K. Klein<sup>1)</sup>, V. Khomenkov<sup>3)</sup>, R. Klanner<sup>3)</sup>, M. Krammer<sup>7)</sup>, K. Kucharski<sup>9)</sup>, W. Lange<sup>2)</sup>, V. Lemaitre<sup>5)</sup>, D. Moya<sup>6)</sup>, J. Marczewski<sup>9)</sup>, A.Mussgiller<sup>2)</sup>, T. Rodrigo<sup>6)</sup>, T. Müller<sup>4)</sup>, J. Sammet,<sup>1)</sup> P. Schleper<sup>3)</sup>, J. Schwandt<sup>3)</sup>, H-J. Simonis<sup>4)</sup>, A. Srivastava<sup>3)</sup>, G.

Steinbrück<sup>3)</sup>, D. Tomaszewski<sup>9)</sup>, S.Sakalauskas<sup>8)</sup>, J.Storasta<sup>8)</sup>, J.Vaitkus<sup>8)</sup>,

A. Lopez Virto<sup>6)</sup>, I. Vila<sup>6)</sup>, E.Zasinas<sup>8)</sup>

(Central Europe Consortium for CMS tracker upgrade)

<sup>1)</sup>Aachen University, Germany, <sup>()</sup> Deutsches Elektronen-Synchrotron DESY, Germany, <sup>9</sup> Institut für Experimentalphysik, Universität Hamburg, Germany <sup>4)</sup> Institut für Experimentelle Kernphysik, Universität Karlsruhe (TH), Germany, <sup>9)</sup> Universite catholique de Louvain, Belgium, <sup>9)</sup> Instituto de Física de Cantabria (UC-CSIC), Santander, Spain ) Institut für Hochenergiephysik der Österreichischen Akademie der Wissenschaften, HEPHY, Vienna, Austria, <sup>3)</sup> Institute of Materials Science and Applied Research, Vilnius University, Lithuania

Institute of Electron Technology, Al. Lotnikow 32/46, 02-668 Warsaw, Poland

As a result of the high luminosity at SLHC, the CMS tracking system with high granularity will be needed and the sensors will have to withstand an extreme radiation environment.



e.g.

On this basis, a new geometry with silicon short strip sensors (strixels) is proposed. In order to understand the behaviour of such devices, test geometries are developed whose performance can be verified and optimized using simulation of semiconductor structures. used the TCAD-ISE (SYNOPSYS package) software in order to simulate the main electrical parameters of different strip geometries, for p-in-n type wafers.

Otilia Militaru



NearStrixels FarStrixels NearStrixels



#### Simulation of electrical parameters of new design of SLHC silicon sensors for large radii



150

Layout 2: Three strips, with

50

X [um]

metal routing, at the same level

100

#### Otilia Militaru



To the readout electronics noise. crucial contribution is given by the backplane capacitance of the bulk and the capacitance between adjacent electrodes (strips). These factors have been studied in order to evaluate the effect of cross talk between nearby Near-Far strips.

For the avalanche breakdown process, the structure demonstrates a good resistivity, the metal routing lower the electric field at the Near Strips junction. From simulations, can be seen the clear variation of the different components of the interstrip capacitance between neighbour strips. The influence of the opposite strip to this parameter starts to be significant when the Far Strip junction is at the same level or closer to Near Strips.



Layout 3: Three strips, with metal



E <u>=1</u>00-

50-

### Silicon detectors with Low Interactions with Material

by INFN group 5 & eight Italian Universities

Lorenzo Vitale (Università di Trieste / INFN)

### SLIM5 BEAM TEST RESULTS FOR THIN STRIPLET DETECTOR AND FAST READOUT BEAM TELESCOPE

Irina Rashevskaya (INFN – Trieste)

### INVESTIGATION OF AN ABNORMAL PATTERN OF THE STRIP LEAKAGE CURRENTS IN MICROSTRIP DETECTORS

### A successful beam test is described in detail

### **Detector options**

The collaboration identified two detector options to reach this goal:

→A new and challenging triple well CMOS Monolithic Active Pixel Sensor (MAPS) with in-pixel signal processing and sparsified capabilities.

Pixel cell is 50x50 µm², active area close to 90% and 100-200 um thick. For more details, talk by M. Villa



→A more traditional, but thin high resistivity doublesided silicon detector with short strips "striplets".

Strips are tilted by 45°, 50 µm pitch, active area 27 x 12.9 mm<sup>2</sup> and 200 µm thick. Strip cap. ~4 pF

For more details, see Poster by I. Rashevskaya

Designed and fabricated by FBK-IRST.



Detail of a corner of the SLIM5 striplet detector.

On some of the sensors a "strange" current patter was observed. The panettone effect

(2nd poster)

20 & 21/27



#### Applications

Such detectors can be used for the layer 0 in a future high-luminosity collider, such as the Super B-factory or the International Linear Collider.

### Investigation of an abnormal pattern of leakage currents in silicon microstrip detectors



Some batches of microstrip detectors fabricated by FBK-irst showed an odd and peculiar pattern of the strip leakage currents :the current of the first and the last few strips is low, whereas all the strips in between have very high current (3-5 orders of magnitude higher). This peculiar phenomenon, common to ALL six different detectors in EACH wafer of the batch, has been called

#### "Panettone effect".



I. Rashevskaya on behalf of the Slim5 Collaboration, Trieste Group

### **Role of surface generation current**



#### Surface generation played a major role.

The high current measured on strip detectors is quantitatively compatible with this surfacegenerated current in the interstrip gaps. It must be concluded that in the gaps between the strips of the detectors the interface has much worse characteristics than in the gated diodes.

### **Proposed explanation for the origin of the effect**

By comparing the technologies of different detector lots fabricated by FBK-irst, we observe that the peculiar 'Panettone Effect' is correlated with the combined presence of two LPCVD-deposited dielectric layers: <u>silicon nitride and TEOS oxide.</u>

This combination produces a high level of stress, which induces defects at the silicon/oxide interface, leading to a high rate of surface generation. These dielectric layers are interrupted in the contact areas between metal and (implanted) silicon. This locally releases the stress in a region around the contact. Since the Bias Rings of the detectors have a continuous contact opening along their length, the local release of the stress can explain the fact that the strips within a certain distance from the Rings have low leakage current. Making use of a modified technology excluding the TEOS oxide, a batch of striplet detectors has been fabricated. They showed no "panettone effect", and have been successfully employed in the SLIM5 beam test at CERN in September 2008

I. Rashevskaya on behalf of the Slim5 Collaboration, Trieste Group

### LASER AND ALPHA PARTICLE CHARACTERIZATION OF A **FLOATING-BASE BJT DETECTOR**

Bipolar junction transistor

BJT detectors are able to measure different types of ionizing radiation:  $\alpha$ -particles (!),  $\beta$ -particles, X- and  $\gamma$ -photons.



### **BJT** detectors



The detector is a Bipolar Junction Transistor whose Collector is the fully depleted high resistivity substrate, while the Emitter and Base implants occupy a few microns under the surface. The reverse biased Base-Collector junction collects the signal charge: as soon as the holes accumulate into the base, due to the BJT effect, an amplified charge is injected from the Emitter to the Collector, generating a few  $\mu$ s wide current pulse. Flowing through the feedback resistor of the OPA, this current pulse is converted into a voltage signal. An Equivalent Noise Charge of 340 e<sup>-</sup> has been obtained with the simple - and inexpensive - setup depicted above [5].

#### Daniele Passeri (Università di Perugia) CHARACTERIZATION OF CMOS ACTIVE PIXEL SENSORS FOR PARTICLE DETECTION: BEAM TEST OF THE FOUR SENSORS RAPS03 STACKED SYSTEM

#### Introduction

Following the mainstream of microelectronics CMOS bulk technology, a third generation of monolithic Active Pixel Sensors for particle detection purposes (called RAPSO3) has been fabricated in 0.18  $\mu$ m CMOS 1P6M technology and tested. Beside electrical characterization and particle detection principle validation, an extensive detector functional test has been carried out. Actually, single chips have been already characterized in terms of response to X-ray photons and  $\beta$  particles.

In this work, in order to check their suitability for vertexing/tracking applications, four stacked CMOS APS sensors featuring 256×256 pixels with 10µm×10µm pixel size have been tested at the INFN Beam Test Facility (BFT), Frascati (Rome), Italy. To this purpose, a dedicated mechanical and electrical set-up has been devised and implemented, allowing for the simultaneous read-out of four sensors arranged in a stacked structure. This work has been carried out within the framework of the SHARPS experiment, supported by I.N.F.N.



Fig. 1; The RAP503 sensor laoyut, featuring  $256{\times}256$  pixels with 10 \mum {\times}10 \mum pixel size, and both small and large n-well diodes.

Third generation of monolithic active pixels MAPS (<u>0.18µm CMOS</u>) in a test beam 4 quadrants with different layouts!

#### Experimental Results

The characterization has been carried out using the Beam Test Facilities at the INFN LNF, Frascati (Rome), Italy. An electron beam featuring energies up to 500MeV has been used. A typical response of the four sensors is illustrated in Fig. 5. The trackin system exploits a self-trigger, using layer and layer IV as telescope.





Fig. 5; Response of the four layers to a particle hit.

Ask Daniele about plans of radiation hardness studies?

#### Signal to Noise and Spatial Resolution

ort probable value 42.0×0.1 ADC

Host probable value

12.8+0.1 ADC

Fig. 11; 5x5 cluster signal distributions; small n-well

(bottom) diode (465MeV e-).

(top) and large n-well

Small n-well

The signal distributions within the cluster are represented in Fig. 10. The Landau signal distributions for a 5x5 pixels cluster are reported in Figs. 11 in terms of ADC counts (1 ADC = 0.62mV). The single pixel noise is 1.67ADC (small n-well) and 1.05ADC (large nwell).

From the generalized  $\eta$ -function distribution [1], the deviation from the "ideal" case of charge division among adjacent pixels can be estimated (assuming that  $\eta$ -functions along x-axis and y-axis are uncorrelated), thus estimating a theoretical spatial resolution limit for particle trajectory of about 0.37 $\mu$ m (Fig. 12).





Fig. 12; Estimated theoretical spatial resolution limits.

### STUDY OF GEIGER AVALANCHE PHOTO DIODES (GAPD) APPLICATIONS TO PIXEL TRACKING DETECTORS

**Main Goal** 

The use of std CMOS tech. APD's in Geiger mode (that is reverse-biased above breakdown) as sensors with integrated logic, for direct particle detection in pixel tracking detectors

### **Exploit PROS and improve on CONS**

The study includes simulation and prototyping (to detailed to explain here)

<ul> <li>Pros:</li> <li>Ionization production of Avalanche starting carrier -&gt; Part. Detect.</li> <li>Std CMOS tech mature and supported for custom design <ul> <li>Integrated and Active Quenching (&amp; active circuits) to minimize avalanche charge, cross-talk and after-pulsing</li> <li>Gate mode (bunch crossing)</li> </ul> </li> <li>Monolithic integration -&gt; System on chip</li> <li>Moderate (low) cost <ul> <li>Vary Low material budget: Depletion region ~1 um ~80 e/b pairs</li> </ul> </li> </ul>	Cons: • Fill factor limited to wells width • Dark count rate (High Geiger eff. even at low excess bias V) • Cross-talk ( to handel lowering the excess bias V) • After-pulsing (trapped carriers & delayed release; worse w/ cooling)
• Very high SNR (but only binary detectors)	<ul> <li>Proto's in HV CMOS:</li> <li>•APD's w/ output buffer: To minimize output load (parasitic) capacitance which impacts performance: time response, after-pulsing, dark count, x-talk</li> <li>•Double APD and APD array:         <ul> <li>•Fill factor ↑: pixel separation minimal (Min. DNTUB distance o(10 µm)).</li> <li>•Different pixels in the same DNTUB (common cathode).</li> <li>• Minimal separation is min. ptub distance (1.7 µm).</li> </ul> </li> </ul>
	<ul> <li>Problem sharing DNTUB: Electrons diffusing in the deep ntub could reach any pixel: electrical "crosstalk"</li> </ul>

Collateral (std) Application: Single photon detection for (astro-)particle physics, medical devices, etc..

## STUDIES SUPPORTING FUTURE DETECTOR OPERATION

Marko Dragicevic (Institute of High Energy Physics of the Austrian Academy of Sciences (HEPHY))

## OPTIMISING THE STRIP GEOMETRY FOR VERY FINE PITCH

## Institute of High Energy Physics





#### **Ingredients**:

- **50 micron** pitch silicon strip sensor with a varying number of **intermediate strips** and different **strip widths**
- Testbeam at CERNs SPS: 120 GeV/c pions

25/27

### **Outcome:**

• Resolution study suggesting the **best strip** geometry for 50 micron pitch strip sensors

First tentative study of dependence of the cluster width on the incident angle for a future p<sub>t</sub> trigger in the tracker

We are waiting for further results from "cluster width on the incident angle "!!!

Filippo Bosi (INFN Pisa)

DEVELOPMENT AND EXPERIMENTAL CHARACTERIZATION OF PROTOTYPES FOR LOW MATERIAL BUDGET SUPPORT STRUCTURE AND COOLING OF SILICON PIXEL DETECTORS, BASED ON MICROCHANNEL TECHNOLOGY Development and Experimental Characterization of Prototypes for Low Material Budget Support Structure and Cooling of Silicon Pixel Detectors, Based on Microchannel Technology



Pixel detectors at future colliders will need to match very stringent requirements on position resolution. The support structure and cooling add important contributions to the total material in the active area.

Advantages of the MICROCHANNELS: due to the high surface/volume ratio, heat exchange trough forced convection of liquid coolant is taking place efficiently, obtaining high thermal conductivities without affecting the stiffness of the structure; the contiguity between the fluid and the circuit dissipating power reduces thermal resistances; uniform temperature on the surface covered by the sensors can be obtained.

Several prototypes with different geometries of micro-machined channels have been realized in ceramics (AIN) and composite materials (CFRP). FEA studies have been validated by the experimental tests performed in the thermofluidodynamics test-bench we recently assembled at the INFN-Pisa laboratory.

#### General Specifications for pixel support :

### Microchannel CFRP single unit

- need to evacuate electronics power (about 20 kW/m2, sensor temperature below 50  $^{\circ}C$ ) - Pixel support (w/o cables and sensors) has to remain as low as possible (below 0,30%  $X_0$ )

700 μm	Peek tube 300 mm int. diam, 50 µm thick	In a thermal convective exchange the film coefficient is: $h = \frac{Nu \cdot k}{k}$
<u>a</u>	CFRP Poltrusion 700 µm square tube	Nu = Nusselt number $D_h$ K = Conductive heat transfer coefficient of the liquid Dh = Hydraulic Diameter of the cooling channel
200	Minimize Dh $\rightarrow$ high pressure drop, (need to find a compromise between	In order to maximize the h value it is important to minimize the hydraulic
Deci MANAgere 11th	pressure drops and film coefficient value).	diameter. This remark points us to the Microchannel technology.
.DUSI, IVI.IVIdSSd, 11 <sup></sup>	TPIS	

Meeting on Advanced Detectors, 24-30 May 2009



### LITHIUM DIFFUSION INTO SILICON-GERMANIUM SINGLE CRYSTAL

Single Crystal 1.1-51, .Ge, Bulk Semiconductor for Detector Audioactore

A. Ruzin <sup>(1)</sup>, N. Abrosimov <sup>(2)</sup>, P. Litovchenko <sup>(3)</sup> (1)Faculty of Engineering, Tel Aviv University, Tel Aviv 69978, Israel (2) Institute for Crystal Growth (IKZ) 12489 Berlin, Germany (3) Institute for Nuclear Research, Ukraine Academy of Science, Kiev, Ukraine

#### ABSTRACT

evicus studies showed that single crystal, bulk own Si  $Ge_{2,1}$  crystals have a great potential for excision applications. The main advantage of  $Ge_{2,2}$  based devices is improved absorption ficiency due to a high atomic number (2) of Ge organed to Si. The buildge of the compound microficator is somewhait unaller than the bandgap silicon, but high enough to allow near room operation experimion.

c main challenge on the path bound plementation of such detectors is the low material origing in probability to increase the residentity and which the material type from p to a by antiopposition by blishmin atoms. The diffusion and it mechanisms of lithium are different in C2 and 2 pronn materials. In addition, the presence of the manima atoms affects the dynamics.

	101 0000	Alex: () 201 Alex: () 701 ()	ADA (7.55)

#### SUMMARY & CONCLUSIONS

In this study, are diffused lathnum atoms impo Si, Ger, single crystals. The compound semiconductme was imple crystals. The compound semiconductme was provident. The results of lithium diffusion at 3000C and 2000C water meteriods. Measurement of lithium contents by 5MMs is very challenging due to the low weight most the votable matter of the element. The spreading revisitance on the other transf provides information most about the other transf provides information most particularly activities of filtingenerations.

It was found that the diffusion is enhanced significantly by the previous effective discussion atoms in the alloy. However, the diffusion is subworthan in the four cose grows without as reported as intensions (Sei U detectory). This can be most likely antibuote both high enhance all oxygen, which reacts with influenations.

Partially drifted sample drives to a doping regions with and without compensation. From the steps of copections, voltage particle, it can be used before compensation results by a to the order of the basis





### Basic wafer Si<sub>x</sub>Ge<sub>1-x</sub>

Smaller bandgap than Si Higher absorption coefficient (high Z) Ge concentration ~ absorption

Li content can change resistivity even change from p- to n-bulk



This is the very last talk

## I WOULD LIKE TO THANK THE ORGANIZERS FOR A TOTALLY PERFECTLY ORGANIZED CONFERENCE



